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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/709,055	04/09/2004	I-Chang Tsao	12404-US-PA	3054

31561	7590	04/03/2008
JIANQ CHYUN INTELLECTUAL PROPERTY OFFICE		
7 FLOOR-1, NO. 100		
ROOSEVELT ROAD, SECTION 2		
TAIPEI, 100		
TAIWAN		

EXAMINER	
ELVE, MARIA ALEXANDRA	

ART UNIT	PAPER NUMBER
3742	

NOTIFICATION DATE	DELIVERY MODE
04/03/2008	ELECTRONIC

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Notice of the Office communication was sent electronically on above-indicated "Notification Date" to the following e-mail address(es):

USA@JCIPGROUP.COM.TW

Office Action Summary	Application No.		Applicant(s)	
	10/709,055		TSAO ET AL.	
	Examiner		Art Unit	
	M. Alexandra Elve		1793	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period **will** apply and **will** expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply **will**, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 07 November 2007.
- 2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-17 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-17 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 09 April 2004 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
1. ☒ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. _____ |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claims 1-5 & 12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Yamazaki et al. (USPAP 2002/0004292) in view of Tanabe et al. (USPN 6,861,614).

Yamazaki et al. discloses a laser annealing apparatus and a method of annealing an amorphous silicon film. Laser light is generated and emitted from a source and then split. The split laser light is used to irradiate the front (primary beam) and the back (secondary beam) of the amorphous semiconductor film. This is shown in figures 3 and 18. It can be seen that the primary beam has a shorter path length than the secondary laser beam. An excimer laser may be used as the laser source. Additionally, an optical system may be used to generate harmonics. Photomasks may be used to generate predetermined patterns. The light source optical system is made up of a light source, an optical system, a reflector, a lens array, a polarization converting element and a condenser lens. (abstract, figures, 0005, 0049, 0061, 0063, 0104, 0128, 0129, 0180)

Although Yamazaki et al. discloses a photomask, the placing of the mask in the optical path is not taught.

Tanabe et al. discloses a system for forming and modifying thin silicon films. A photomask is used to project a light pattern, which exposes the thin film(s) and thus modifies them.

It would have been obvious to one of ordinary skill in the art at the time of the invention to use a photomask in the optical path, as taught by Tanabe et al. in the Yamazaki et al. system because allows more control of the film modification.

Duplication of parts was held to have been obvious. In re Harza 124 USPQ 378.

Claims 6-11 & 13-17 are rejected under 35 U.S.C. 103(a) as being unpatentable over Yamazaki et al. and Tanabe et al., as stated in the above paragraph and further in view of Jung (USPN 6,825,493).

Yamazaki et al. and Tanabe et al. do not teach (i) a photomask with a stripe pattern, (ii) a lens disposed on the optical path in front of the photomask and (iii) annealing amorphous silicon films in regions.

Jung discloses a silicon crystallization method using a photomask having a stripe pattern (38) and a condenser lens (40) is in front of the photomask. Figure 9b shows a striped crystallization pattern.

It would have been obvious to one of ordinary skill in the art at the time of the invention to use a striped photomask, a lens in front of the mask and annealing regions as taught by Jung in the Yamazaki et al. and Tanabe et al. apparatus and process because these are merely variations of silicon recrystallization using laser annealing.

Furthermore, it would have been obvious to use more than one photomask because it would enhance the efficiency of producing the product.

Response to Arguments

Applicant's arguments filed 11/07/07 have been fully considered but they are not persuasive.

Applicant argues that Yamazaki et al. fails to teach two masks concurrently. The examiner respectfully disagrees because Yamazaki et al. teaches the use of multiple photomasks.

Applicant argues that Yamazaki et al. does not teach the placement of the photomasks. The examiner respectfully notes that the placement of photomasks is taught by Tanabe et al. In response to applicant's arguments against the references individually, one cannot show nonobviousness by attacking references individually where the rejections are based on combinations of references. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981); *In re Merck & Co.*, 800 F.2d 1091, 231 USPQ 375 (Fed. Cir. 1986).

Applicant argues that Yamazaki et al. does not teach the use of a beamsplitter. The examiner respectfully notes that a reflector is taught (functional equivalent substitute for a beamsplitter).

Applicant argues that Jung teaches only a single mask. In response to applicant's arguments against the references individually, one cannot show nonobviousness by

attacking references individually where the rejections are based on combinations of references. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981); *In re Merck & Co.*, 800 F.2d 1091, 231 USPQ 375 (Fed. Cir. 1986).

Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire **THREE MONTHS** from the mailing date of this action. In the event a first reply is filed within **TWO MONTHS** of the mailing date of this final action and the advisory action is not mailed until after the end of the **THREE-MONTH** shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than **SIX MONTHS** from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to M. Alexandra Elve whose telephone number is 571-272-1173. The examiner can normally be reached on 7:30-4:00 Monday to Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Roy King can be reached on 571-272-1742. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Art Unit: 1793

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

March 31, 2008.

/M. Alexandra Elve/
Primary Examiner, Art Unit 1793